REMARKS

Claims 1-19, 21-27 and 29-34 are pending in the present Application. By the present amendment, claims 1, 12, and 22 are amended to add the limitations of claim 8 and the cooling range set forth in claim 25 and claims 25, 32, and 33 are amended to add the limitation that the cooling is to occur in the sample probe.

The Applicant respectfully requests that this Amendment be entered and that the present application be reconsidered in light of the foregoing claim amendments and the following remarks.

I. EXAMINER INTERVIEW

On October 18, 2005, the undersigned, along with Harry Laxton (also of Hunton & Williams) had a telephone interview with Examiner Arlen Soderquist (Examiner) regarding the Office Action issued July 21, 2005. The Applicant appreciates the courtesy and assistance extended by the Examiner during this interview.

The specific purpose of the interview was to discuss the Examiner's use of a 1976 article by Heyman and Turner ("Heyman Paper") in combination with a Japanese article by Yokoyama et al. (Yokoyama Paper) to construct an obviousness rejection. Prior to the interview, the undersigned had forwarded a copy of page 2 of the Yokoyama Paper with a penciled-in translation of the terms used in Figures 1 and 2. A copy of this page is enclosed as Attachment 1 to this Response.

In the interview, the undersigned pointed out that the Examiner had cited Yokoyama as suggesting that a converter placed "at the sampling point" would require heating. The Examiner's assertion was based on the apparent use of heated lines in the systems depicted in Figures 1 and 2 of the Yokoyama Paper. The translation of these figures (see Attachment 1) indicates that neither figure depicts an actual emission sampling system. The systems shown in these figures are, instead, merely systems for testing the disclosed methods and the converter setup. The undersigned asserted that the heating of the lines appears to be for the purpose of heating the gas to temperatures that would be similar to what would be experienced with a

sample gas. Based on this information, the Examiner stated that that he would need to get a full English translation of the Yokoyama Paper for any further examination.

The interview then focused on method claim 25, which recites cooling the gas to a temperature below 350 degrees Fahrenheit and above the dew point of the gas. In the Office Action, the Examiner stated that it would be "inherent in the Heyman system [that there] would be a loss of heat when the temperature of the gasses contact an environment at a temperature lower than their own temperature." The undersigned pointed out that there is nothing in Heyman that talks about establishing a particular temperature range of the gas coming out of the sampling probe.

As noted in the Interview Summary dated October 18, 2005, the Examiner agreed that claim 25 would be allowable over the prior art of record if it was amended to state that the cooling step is carried out in the sampling probe and that similar allowability would be attained by amending all other independent method and system claims. The Examiner stated that this would be sufficient to allow entry of an amendment after final but that the claims would still be subject to additional search.

As also noted in the Interview Summary, the Examiner agreed to enter the amendment described above and to obtain a full translation of the Yokoyama Paper.

II. THE CLAIMS ARE PATENTABLE OVER THE CITED ART

In paragraph 2 of the Office Action, claims 1-19, 21-27, and 29-34 (all pending claims) were rejected under 35 U.S.C. 103(a) as being assertedly unpatentable over the Heyman Paper in view of the Yokoyama Paper, a paper by R.D. Jacquot et al. ("Jacquot Paper"), Burrows, U.S. Patent No. 5,739,038 (Burrows Patent") and Yamaki et al., U.S. Patent No. 4,073,866 ("Yamaki Patent") or Hara et al, Japanese App. No. 53-37591 ("Hara Application"). The Applicants respectfully traverse this rejection.

Claims 1, 12, 22, 25, 32 and 33 have all been amended according to the Examiner's suggestion regarding the additional recitation that cooling is carried out in the sampling probe.

The Applicants respectfully submit that the combined teachings of the cited prior art references do not teach, disclose or suggest the features of independent claims 1, 12, 22, 25, 32 and 33, as amended. Specifically, there is no disclosure or suggestion of systems as recited in claims 1, 12 and 22 having the arrangement of components recited and having a sampling device comprising a sample probe that includes means for cooling the sample gas in the sample probe to a temperature below about 350 °F but above a dew point temperature of the sample gas. Further, there is no disclosure or suggestion of methods as recited in claims 25, 32 and 33 that include the recited steps including cooling the sample gas in the sample probe to a temperature below about 350 °F but above a dew point temperature of the sample gas.

For at least the above reasons, the Applicants respectfully submit that the rejection of claims 1, 12, 22, 25, 32 and 33 under 35 U.S.C. 103(b) should be withdrawn.

2. Dependent Claims 2-11, 13-19, 21, 23, 24, 26, 27 and 29-31

Each of claims 2-11, 13-19, 21, 23, 24, 26, 27 and 29 is dependent on one of the independent claims discussed above. Because each of those independent claims is patentable over the cited combination of references, the Applicants submit that the dependent claims are also patentable. Accordingly, the Applicants respectfully submit that the rejection of claims 2-11, 13-19, 21, 23, 24, 26, 27 and 29-31 under 35 U.S.C. 103(b) should also be withdrawn

III. <u>CONCLUSION</u>

The Applicants have amended the claims in accordance with the Examiner's suggestions. For the reasons set forth above and in the Examiner's Interview Summary, the Applicants respectfully submit that claims 1-19, 21-27 and 29-34 are in condition for allowance. The Applicants therefore request that the present Amendment be entered and that the application be allowed and passed to issue.

Should the Examiner believe anything further is desirable in order to place the application in even better condition for allowance, the Examiner is invited to contact the Applicants' undersigned representative.

Respectfully submitted,

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- 2. 除湿器を通したのち分析計へ 導入 した場合
- 水中へパブリングして除湿器 を通したのち分析計へ導入した 場合

の測定値を比較した.

2.2 サンブリング用コンパータ 高温における NO2 が NO 〜分解 する過程を調べるため、外部をリポ ンヒータで加熱したガラス管にNO2 を流す簡単な定性実験を行なった. その結果、NOsは NO へ分解しや すく,ガラス管中にポイラ排ガス中 のカーポンまたは活性炭を充てんし た場合にはさらに多くのNO2が NO に分解した. これらの結果をもとに 活性炭を使用したサンプリング用 NO₂→NO コンパータを試作(第1 図)し、性能試験を行なった。 コン バータはステンレス製で,電気加熱 炉による子熱部とシーズヒータを巻 いた活性炭光でんぽから なってい

2.3 サンブルガス中の NO₂ の吸 収除去

サンプルガス中のNOまたはNO2 を別個に測定するには,まずサンプ リング用コンバータにより 正確 な NOx 低 (NO+NOx とする) を求 め、NO. NO2のいずれか一方の低 が水まれば他の低も求められる. ゆ えに、いずれか―方のみを吸収する 液にサンブルガスを通したのち分析 する方法を採用した。しかし、 NO のみを吸収する吸収剤は実験した範 囲では見つからなかったので、 NO は吸収せず NO₂ のみをよく吸収す る吸収液の採索を中心に実験した. 実験は、吸収剤のほか液の pH、ガ

device ス流量、吸収びんの容量、液量、液深さ、ガス出口ノズルの形状な とを変えて行なった。

Air

N2 gas

humidification

和保险

2.4 NOの O₃ 酸化により生成した NO₂ の分析

Oa を酸化剤として NO を NOaにする脱硝プロセスのような場合 Kは、 NO_2 以上に酸化された窒素酸化物の生成(N_2O_6 など)が考 えられる。そこで、このような場合、分析方法への影響を調べるた め O。 発生機を使用(第2図)し、化学発光法分析計と紫外線吸収式 NO2 計を併用して NOx, NO, NO2 を測定した。さらに、生成さ れた NO, NO, 以外の窒素酸化物の存在を調べるため、O₃/NO の 種々の値のガスを吸収液に1時間吸収させたときの液中に存在する それぞれの NO、を、文献(1)の改良法により分析した。

2.5 ボイラ掛ガスに対する実用例

以上に述べた分析方法を実際のポイラ排ガスによるOs 酸化法型 式脱硝法テストプラントに適用した. 煙道にサンプリング用 NO₂ →NO コンバータと NO₂ 吸収びんを並列に設置し、化学発光法分 析計により分析した場合、コンパークおよび吸収びんを用いず化学

· ribbon heater - Chile charter part が改良 排ガス中の資素酸化物濃度測定法 preheater method 1 NOy NO analyse flow metre 15年20年 (ATE 603148357 活性及光て人 preprocess が iš iš 在政治政 Advanced (dehumidi NO_PANKU ficultos deyke. Sampling FALLCON SEL N٠ N₂ NO OT NO. NO NO SO Mos absorbing bottle UV absorbing metho Standard Temperature recording (NO2) analyzer compressed gas サンフリング月 NOY NO コンバーグ ましびサンブルガス中の NO 吸収除 決定 絵 遊 所 Fig. 1 Schematic flow diagram of an apparatus for testing NO2-NO converter (0.2) Osopherotion NO₂ absorber Nov-2 NO (devices) Osmetre converter Chemilumines ence method NO2, NO NO_z analyzer 化学兄弟进 NO NOSA water temperature controller NO.吸收 No absorption & removal 经外款吸收法 NOIの折針

> Fig. 2 Schematic flow diagram of an apparatus for determining nitrogen oxides formed by ozone oxidation of NO

所な図 NO to 数化して生成する炎素酸化物の分析実験整配

ribbon header

発光法分析計および架外線吸収法 NOz 計へテフロン管で直接導い て分析した場合、PDS 法による手分析の場合の結果を比較した.

UV absorbing methe

NO2 analyzer

3. 箱果および考察

3.1 凝縮水分中への NO2 の吸収と NO の発生

湿りガスの場合には、途中のラインおよび除湿器において NO: はほぼ(1)式に従って吸収され、吸収された NO2の約1/3の NO が発生することが確認された(第1姿)。 とくに、除機器での NO2 の吸収が大きい。これは、前処理装置が加圧・低温状態(0.2~1.2 kg f/cm², 2 °C) で操作されているので、NO。の水分中への 吸収 がより起りやすくなっているものと思われる。圧力の影響が非常に 大きいので、できるかぎり圧力を低く抑えるべきである.

NO2 標準ガス を 化学発光法分析計で直接分析した場合、いくぶ ん低い値となっているのは、分析器内の NO₂→NO コンパータの 転換効率が 100 %でないためと思われる.一般に市販されている製 品では、転換効率:90~95%のものが多い。 しかも、その転換効率